

Notice of References Cited	Application/Control No. 10/536,774		Applicant(s)/Patent Under Reexamination SHIRAFUJI ET AL.	
	Examiner KENISHA V. FORD		Art Unit 2812	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2004/0006249 A1	01-2004	Hoshino et al.	570/123
*	B	US-2006/0264059 A1	11-2006	Kobayashi et al.	438/758
*	C	US-2004/0161946 A1	08-2004	Tsai et al.	438/778
*	D	US-6,429,518 B1	08-2002	Endo, Shunichi	257/753
*	E	US-2006/0040507 A1	02-2006	Mak et al.	438/758
*	F	US-2004/0175501 A1	09-2004	Lukas et al.	427/255.28
*	G	US-2005/0176230 A1	08-2005	Sieber et al.	438/609
*	H	US-6,593,246 B1	07-2003	Hasegawa et al.	438/736
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Shirafuji et al., "PlasmaCopolymerization of C6F6/C5F8 for Application of Low-Dielectric-Constant Fluorinated Amorphous Carbon Films and Its Gas-Phase Diagnostics Using In Situ Fourier Transform Infrared Spectroscopy", 11 May 2004, Japanese Journal of Applied Physics, Vol. 43, No. 5A, pp. 2697-2703			
	V				
	W				
	X				

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.